

## Adhesion and Friction in Polymer Films on Solid Substrates: Conformal Sites Analysis and Corresponding Surface Measurements

Rong An,<sup>a,b</sup> Liangliang Huang,<sup>c</sup> Kenneth P. Mineart,<sup>b,†</sup> Yihui Dong,<sup>d</sup> Richard J. Spontak,<sup>b,e</sup> and Keith E. Gubbins<sup>\*,b</sup>

<sup>a</sup> Herbert Gleiter Institute of Nanoscience, Nanjing University of Science & Technology, Nanjing 210094, P.R. China

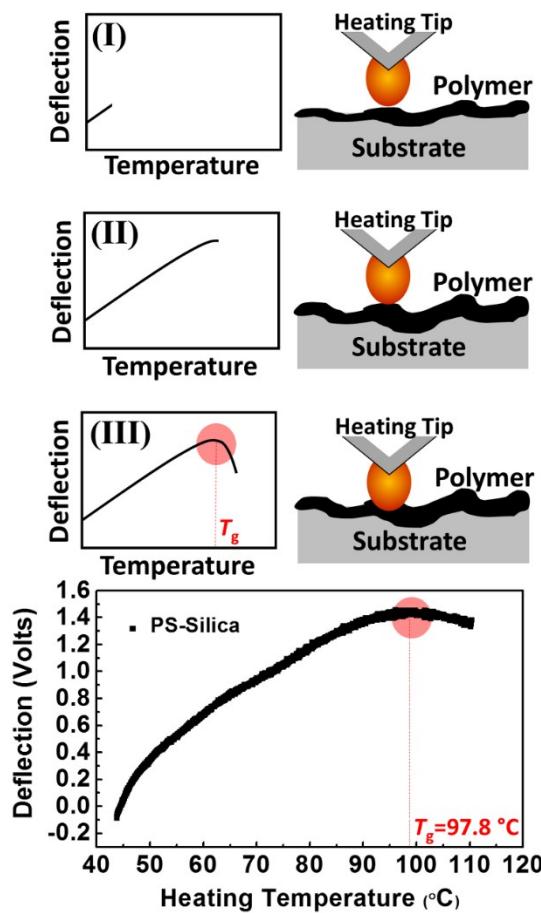
<sup>b</sup> Department of Chemical and Biomolecular Engineering, North Carolina State University, Raleigh, NC 27695, USA. Corresponding Author: Keith E. Gubbins,\* Phone: 919-513-2262. Fax: 919-515-3465. E-mail: keg@ncsu.edu.

<sup>c</sup> School of Chemical, Biological and Materials Engineering, University of Oklahoma, Norman, OK 73019, USA

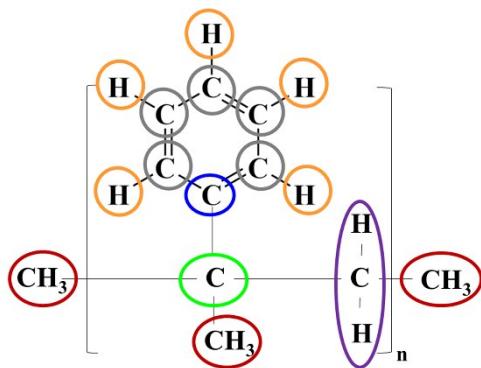
<sup>d</sup> State Key Laboratory of Materials-Oriented Chemical Engineering, Nanjing Tech University, Nanjing 210009, P.R. China

<sup>e</sup> Department of Materials Science and Engineering, North Carolina State University, Raleigh, NC 27695, USA

† Present Address: Materials Science & Engineering Division, National Institute of Standards & Technology, Gaithersburg, MD 20899, USA



**Fig. S1** Schematic diagram showing the basic operating principle of Nano-TA and a representative deflection curve for a PS film (thickness = 340 nm) on a silica surface.



**Fig. S2** Polymer structures and bead center locations chosen for poly( $\alpha$ -methylstyrene) (PAMS).

**Table S1. Site mole fractions and potential energy parameters<sup>1</sup> for PAMS with  $M_w = 450$  kDa (OPLS force field)**

PAMS	$\epsilon_v / k_B$ (K)	$x_v$	$\sigma_v$ (nm)
CH <sub>3</sub> (sp <sup>3</sup> ) <sup>2</sup>	88.1	0.0004	0.390
CH <sub>2</sub> (sp <sup>3</sup> ) <sup>2</sup>	59.4	0.071	0.390
C (aliphatic) <sup>3</sup>	33.2	0.071	0.350
C (aromatic) <sup>3</sup>	35.2	0.071	0.355
H (aromatic) <sup>3</sup>	17.4	0.357	0.242
C (aromatic link) <sup>3</sup>	38.3	0.357	0.355

**Table S2. Site mole fractions and potential energy parameters<sup>4, 5</sup> for PMMA with  $M_w \approx 100$  kDa (OPLS force field)**

PMMA	$\varepsilon_v/k_B$ (K)	$x_v$	$\sigma_v$ (nm)
CH <sub>3</sub> (sp <sup>3</sup> ) <sup>2</sup>	88.1	0.143	0.390
CH <sub>2</sub> (sp <sup>3</sup> ) <sup>2</sup>	59.4	0.143	0.390
C (sp <sup>3</sup> ) <sup>3</sup>	33.2	0.143	0.350
C (carbonyl) <sup>3</sup>	52.8	0.143	0.375
O (carbonyl) <sup>3</sup>	106	0.143	0.296
O (ether) <sup>6</sup>	85.6	0.143	0.300
CH <sub>3</sub> (ether) <sup>2</sup>	85.6	0.143	0.380

**Table S3. The structural parameters of Au<sup>7, 8</sup> and silica surfaces,<sup>9</sup> and parameters for the reference system to calculate wetting parameters for PMMA-Au and PAMS-silica systems**

	silica	Au
$\rho_s$ (nm <sup>-3</sup> )	44.2	0.59
$\Delta_s$ (nm)	0.220	0.288
$\sigma_{ss}$ (nm)	0.270	0.257
$\varepsilon_{ss}/k_B$ (K)	230	5310
PMMA	$\varepsilon_{xs}/k_B$ (K)	/
	$\sigma_{xs}$ (nm)	/
		0.308

	$\varepsilon_x/k_B$ (K)	69.6
	$\sigma_x$ (nm)	0.356
	$\alpha_{wx}$	/
		0.141
	$\varepsilon_{xs}/k_B$ (K)	86.3
	$\sigma_{xs}$ (nm)	0.287
PAMS	$\varepsilon_x/k_B$ (K)	32.1
	$\sigma_x$ (nm)	0.304
	$\alpha_{wx}$	0.051
		/

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